

FIG.1

STRUCTURE DIAGRAM OF
EACH CHAMBER AND ITS PERIPHERY

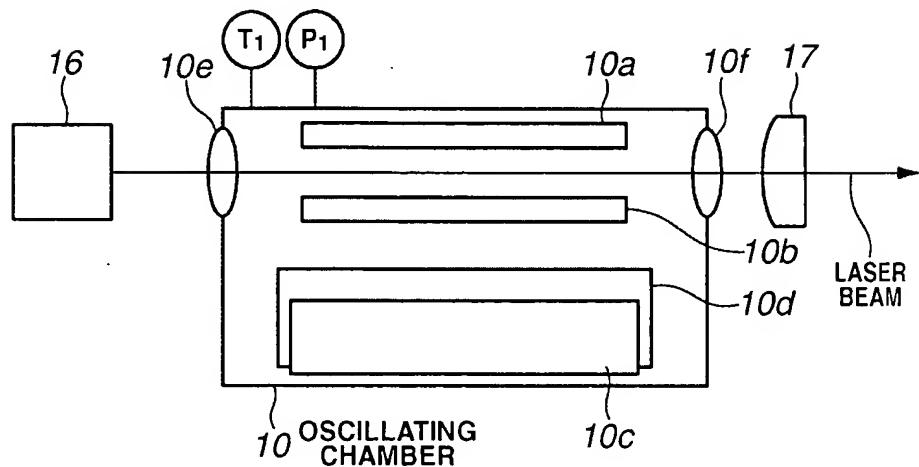


FIG.2A

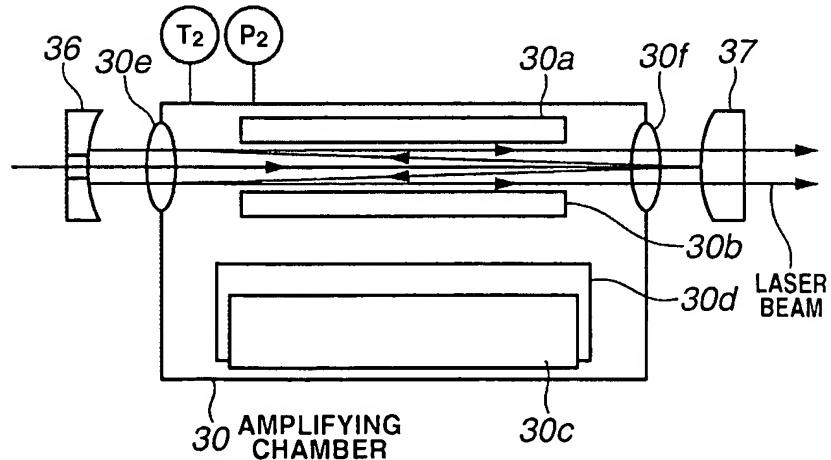


FIG.2B

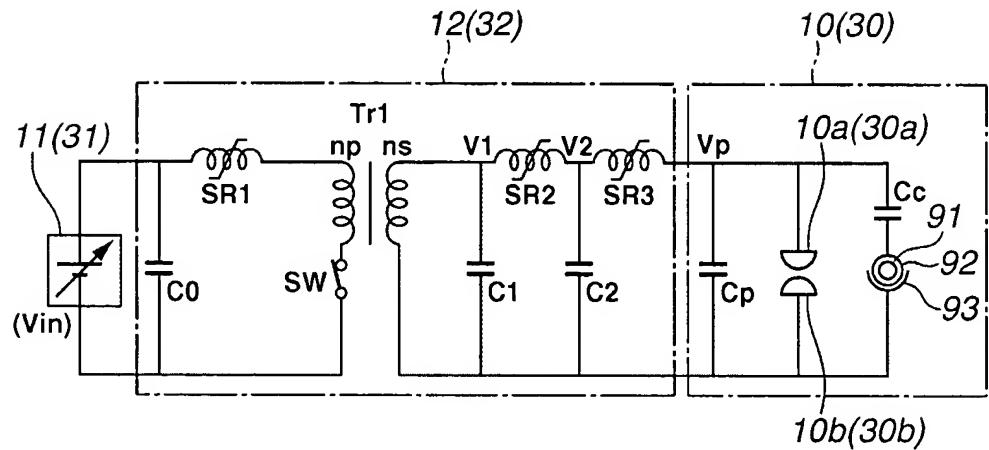


FIG.3A

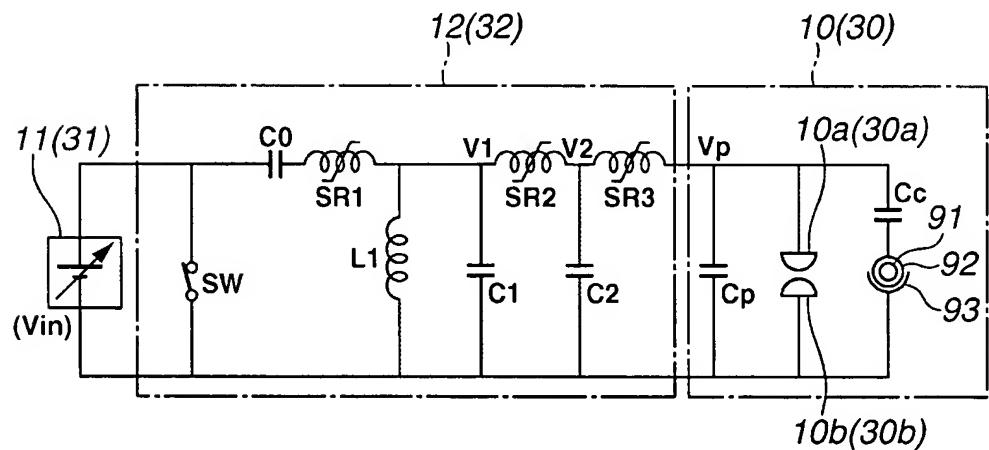


FIG.3B

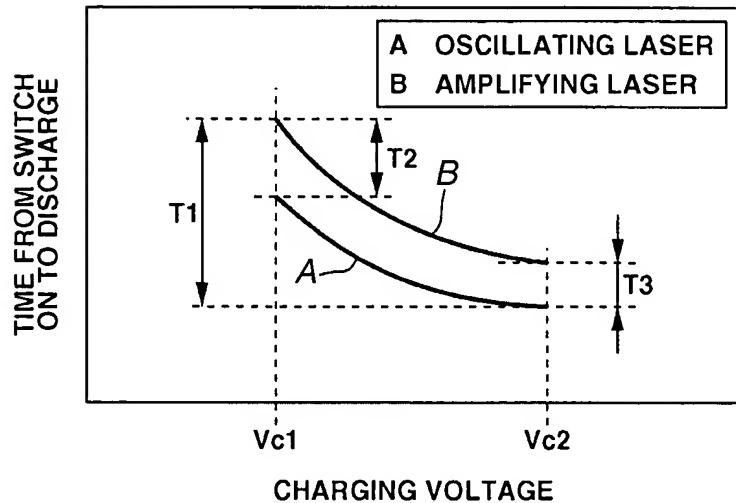
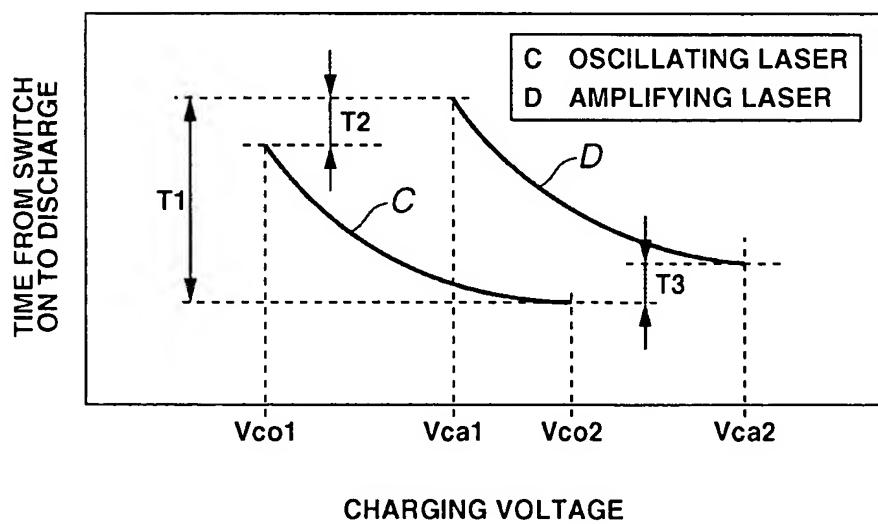


FIG.4



CHARGING VOLTAGE

FIG.5

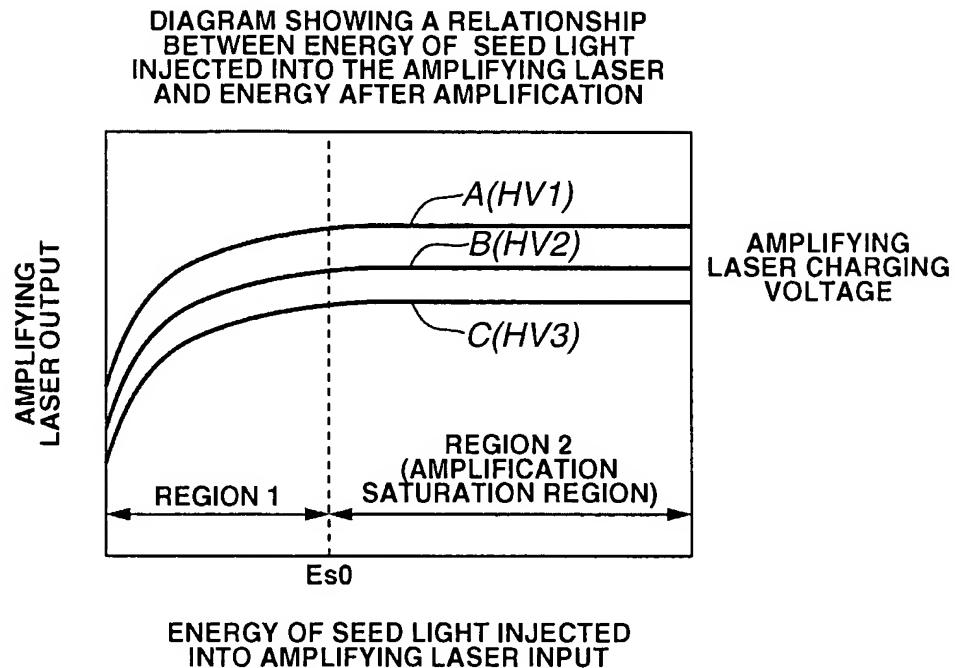
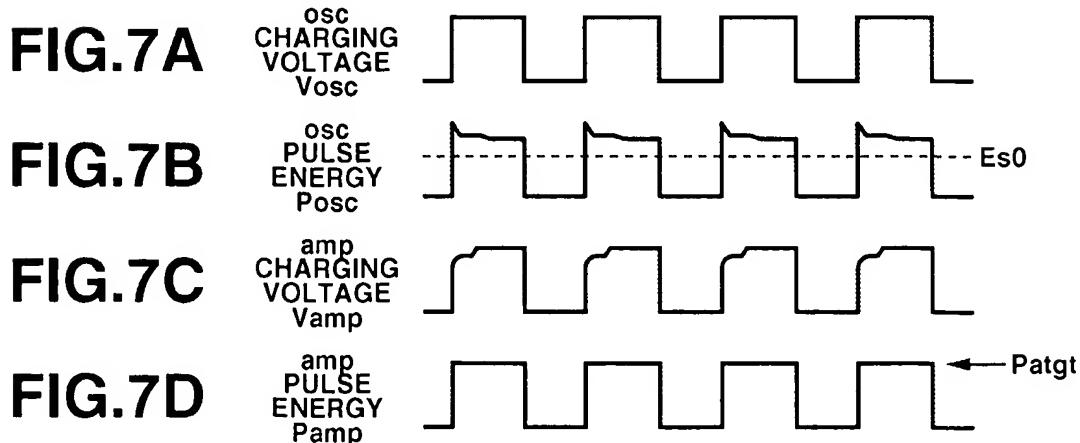


FIG.6

DIAGRAMS SHOWING INDIVIDUAL CHARGING VOLTAGES
 AND INDIVIDUAL PULSE ENERGIES IN FIRST CONTROL EXAMPLE



CONTROL FLOWS OF OSCILLATING
 LASER AND AMPLIFYING LASER

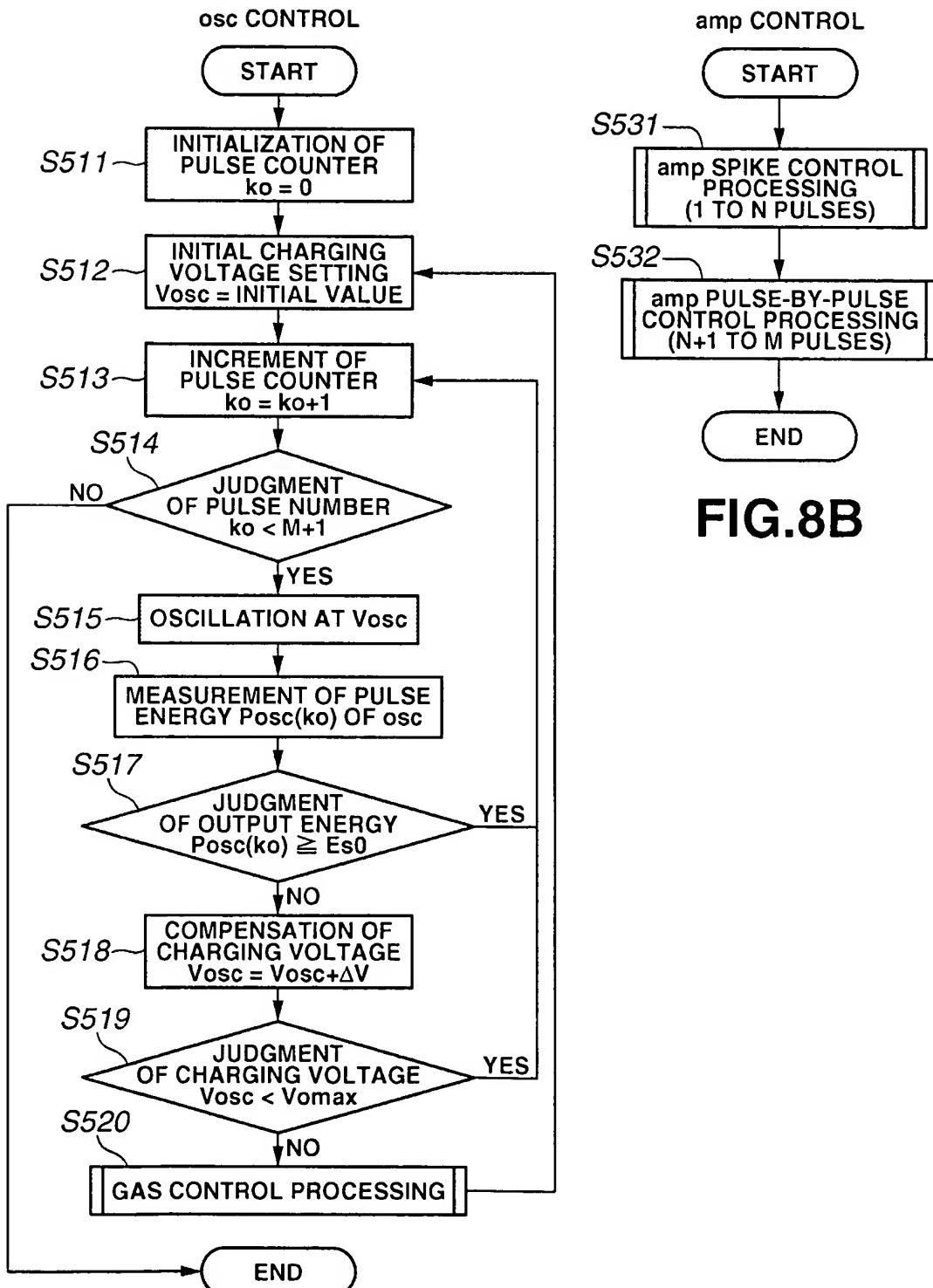


FIG.8B

FIG.8A

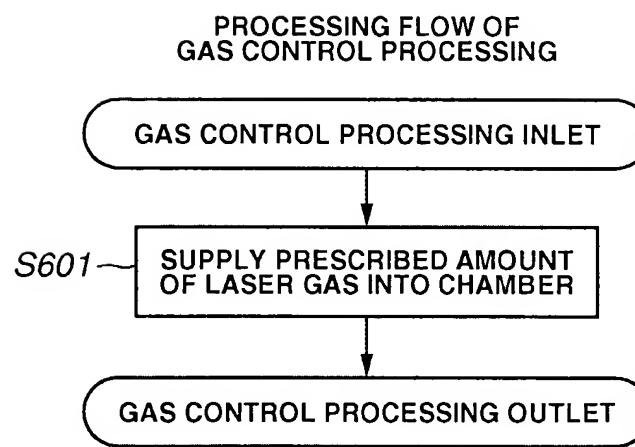


FIG.9

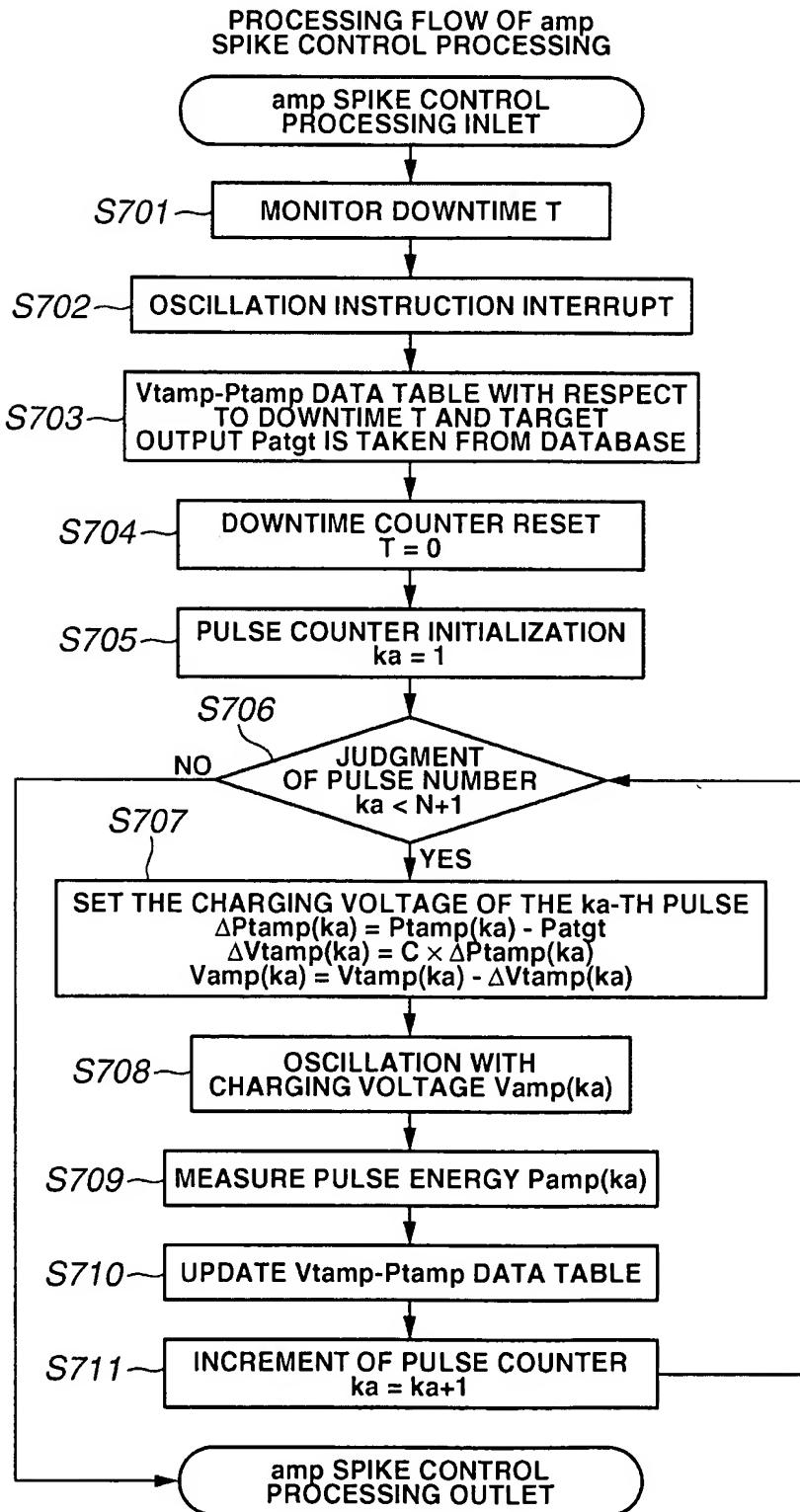


FIG.10

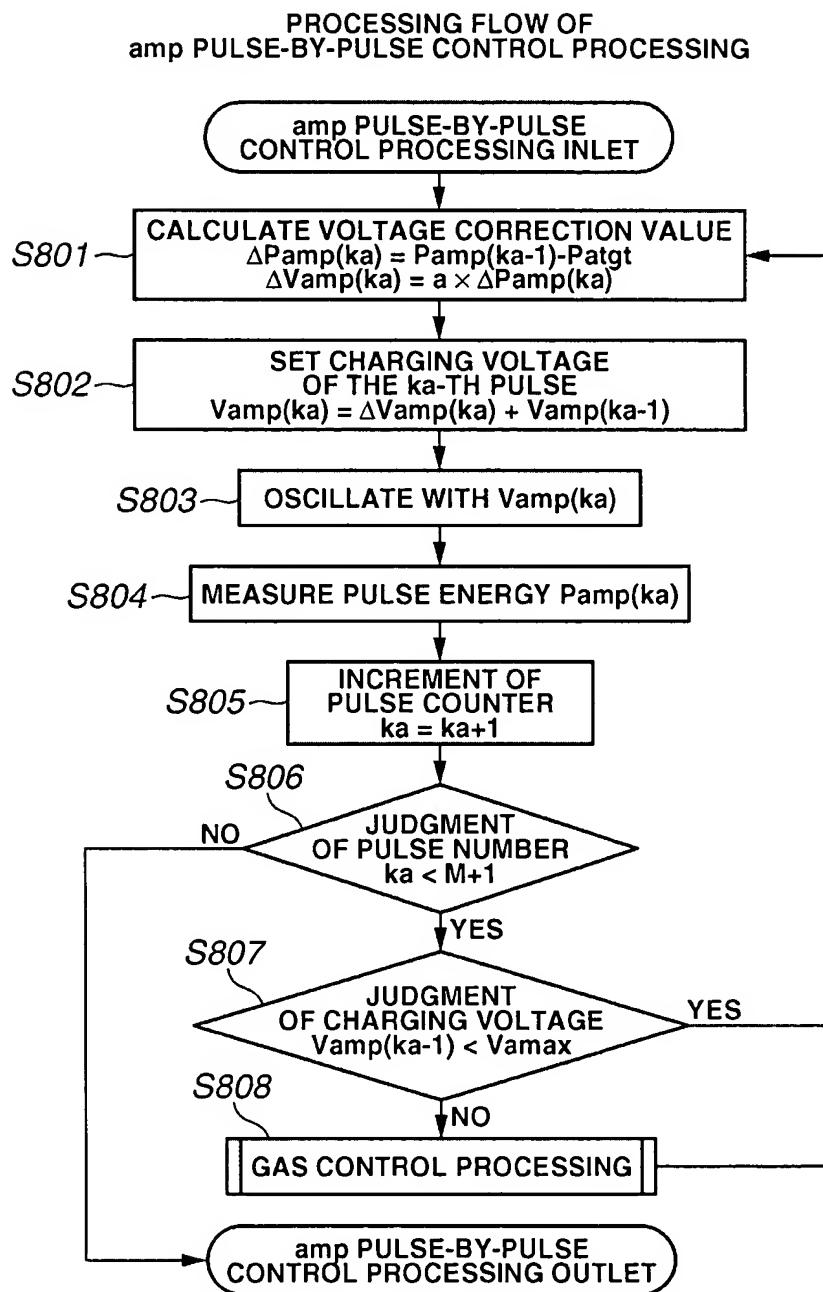


FIG.11

CONTROL FLOWS OF OSCILLATING
 LASER AND AMPLIFYING LASER

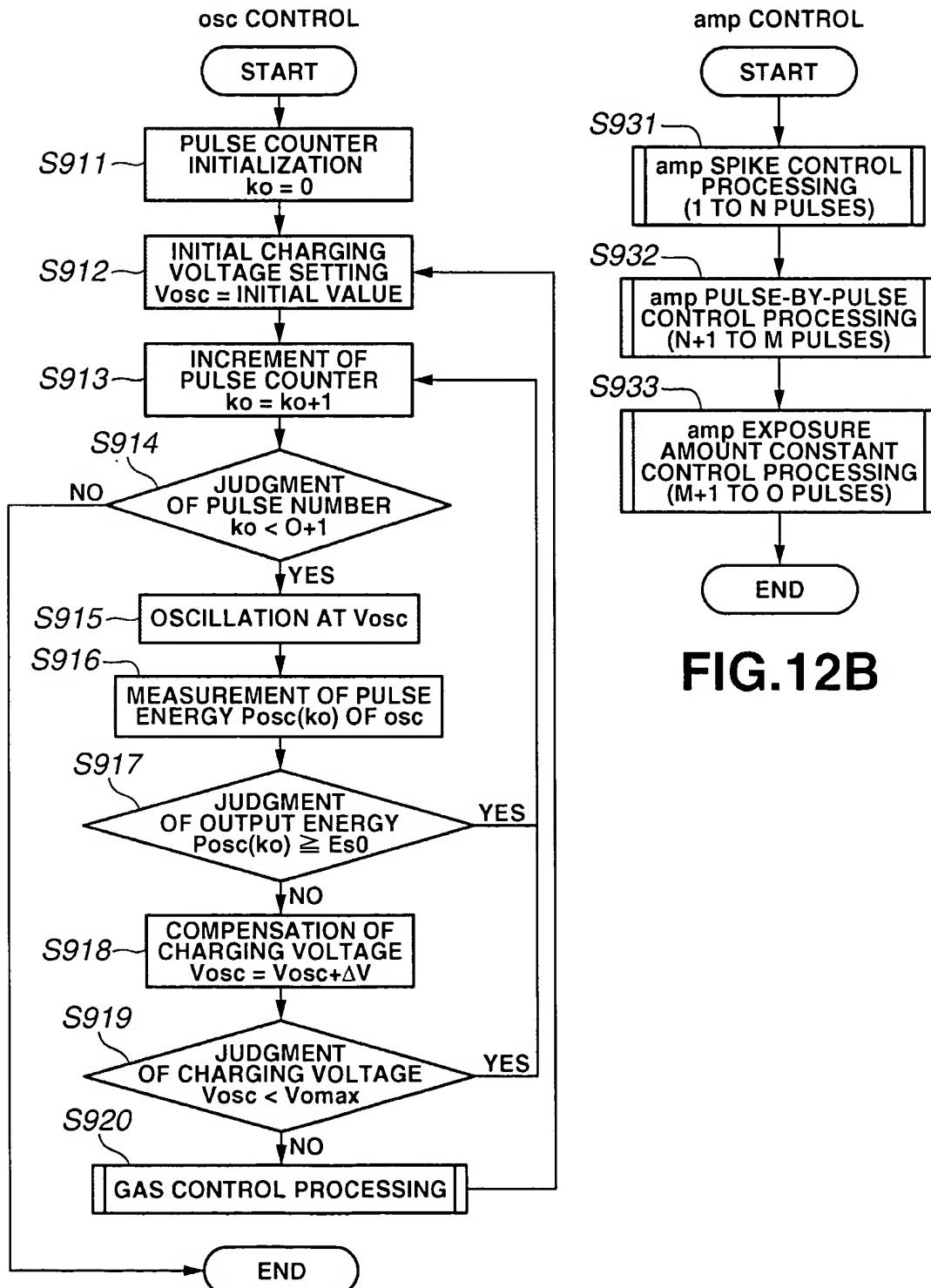


FIG.12B

FIG.12A

PROCESSING FLOW OF amp EXPOSURE
 AMOUNT CONSTANT CONTROL PROCESSING

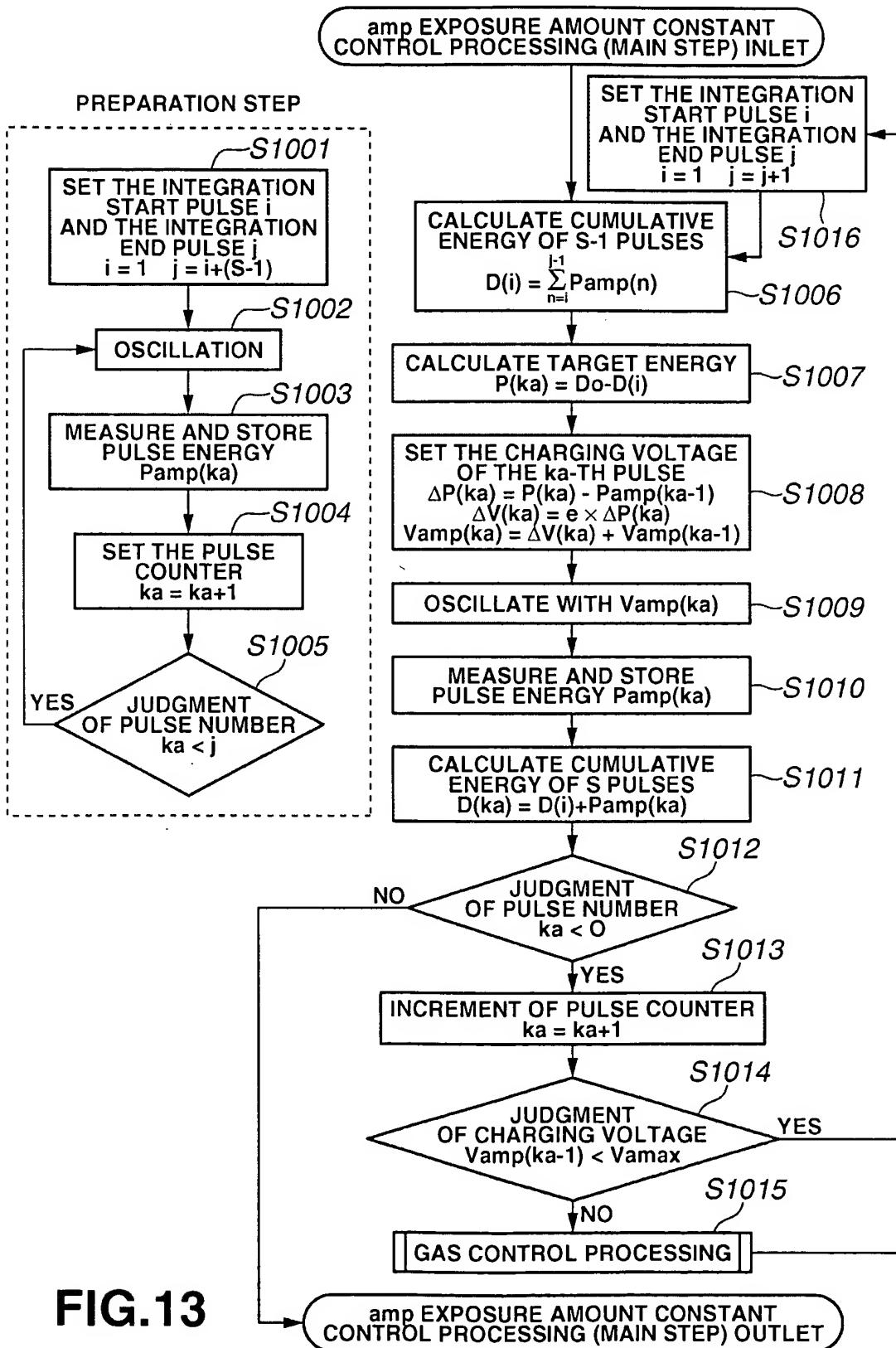


FIG.13

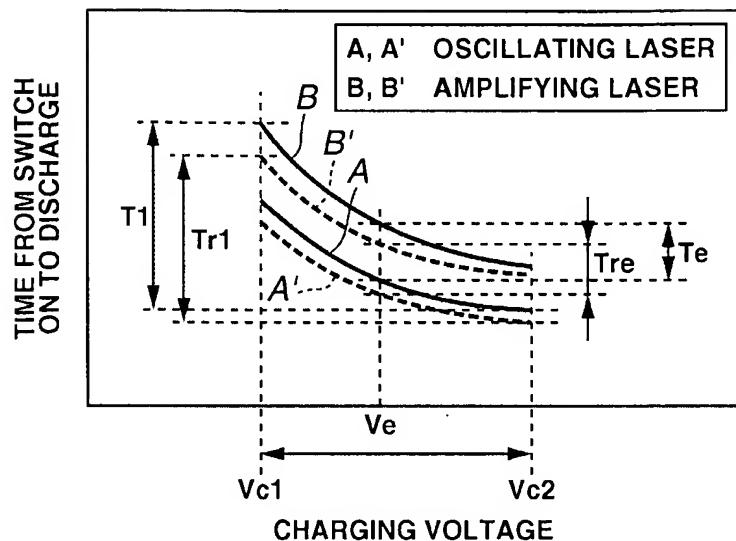


FIG.14

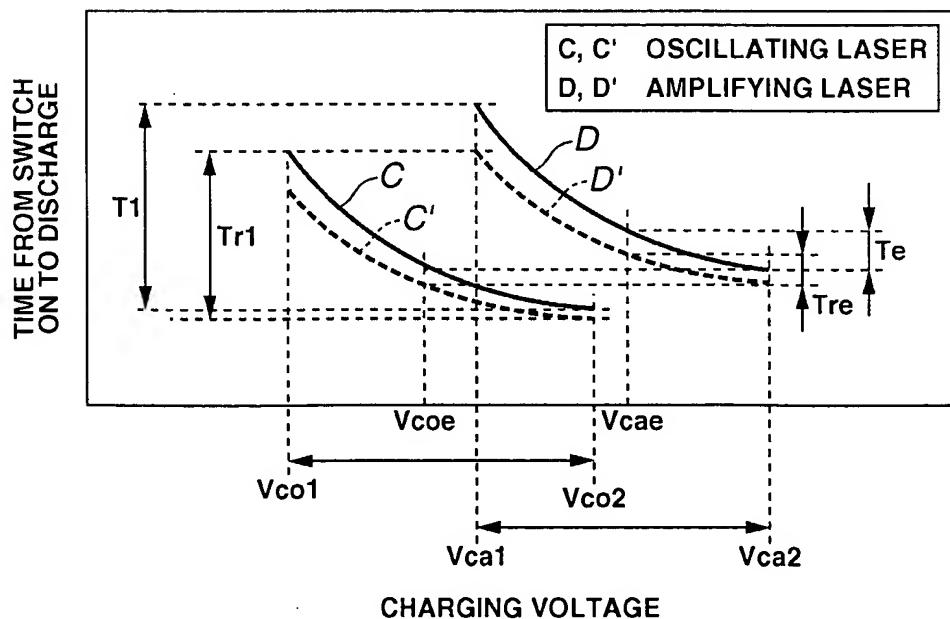


FIG.15

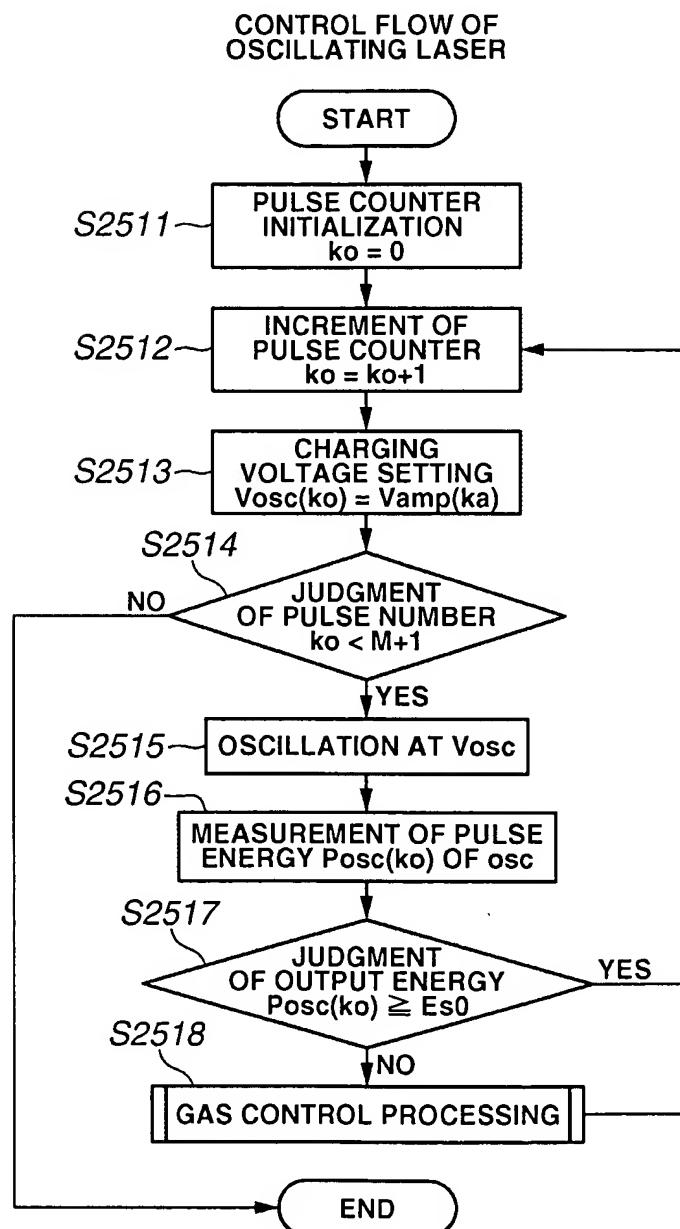


FIG.16

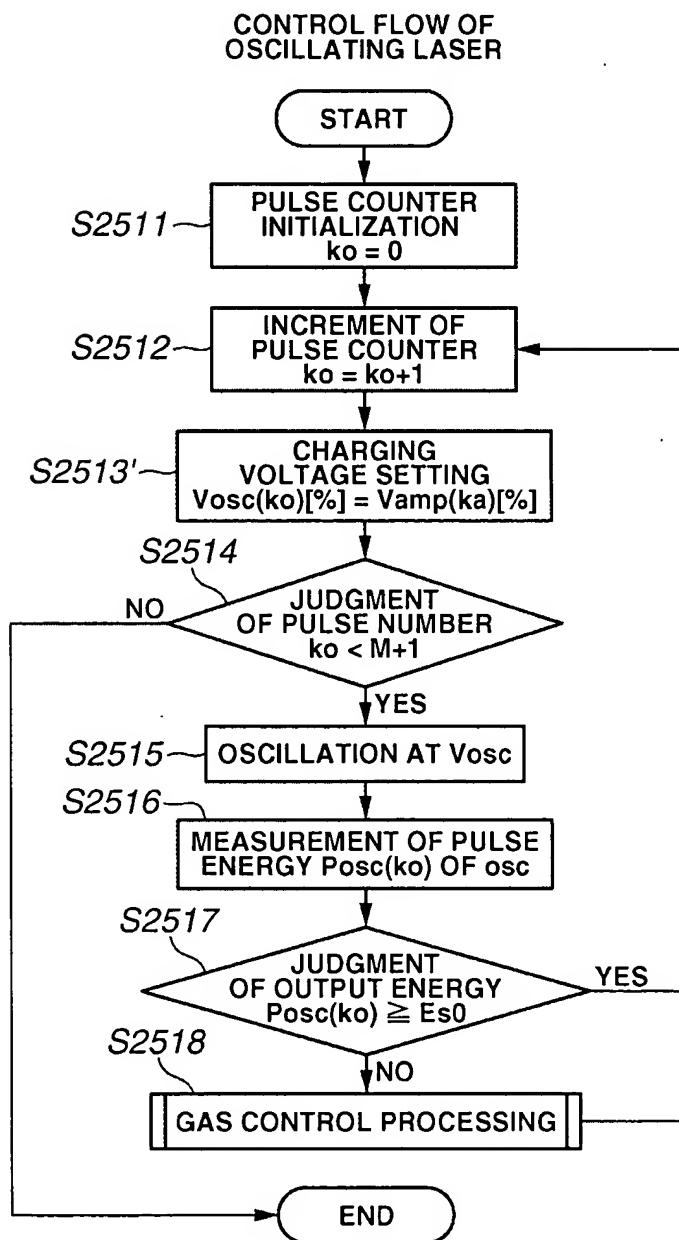


FIG.17

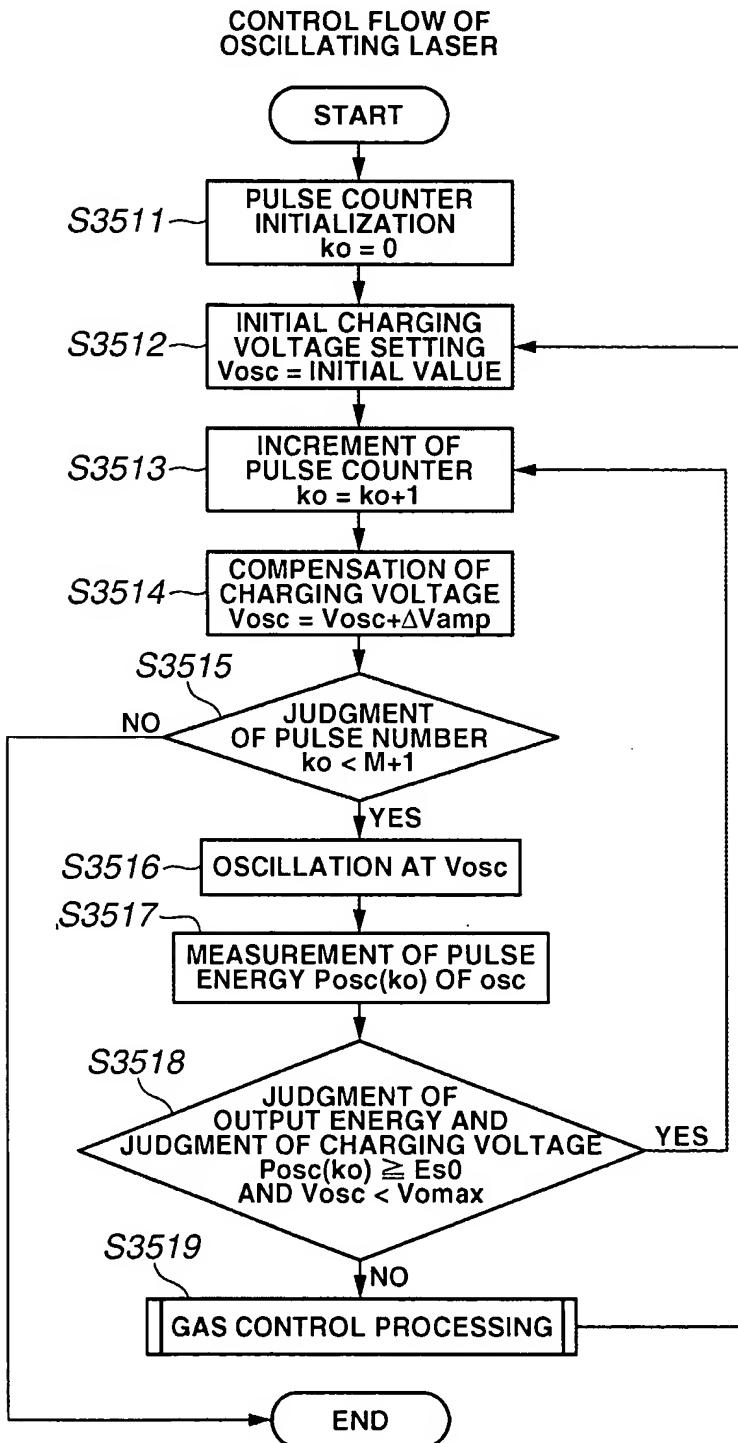
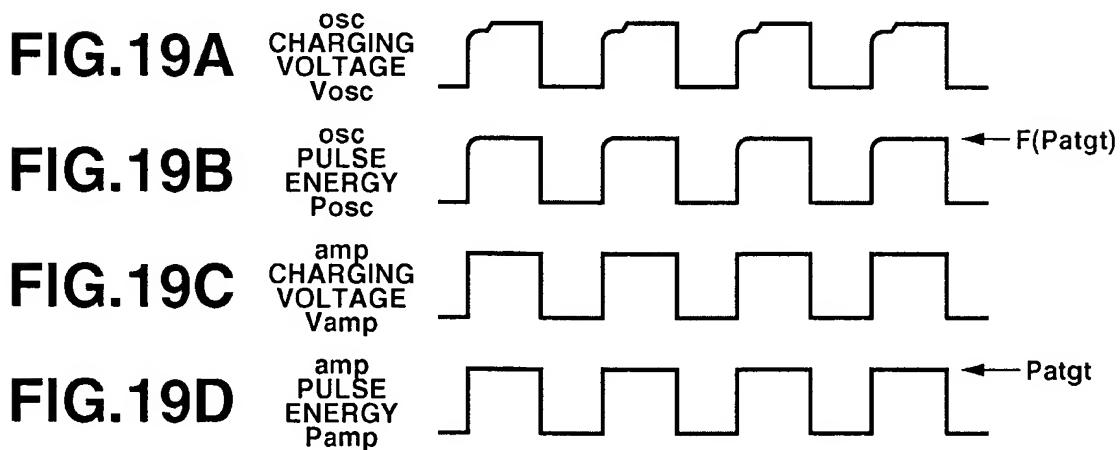


FIG.18

DIAGRAM SHOWING INDIVIDUAL CHARGING VOLTAGES
AND INDIVIDUAL PULSE ENERGIES IN SECOND CONTROL EXAMPLE



CONTROL FLOWS OF OSCILLATING LASER
 AND AMPLIFYING LASER

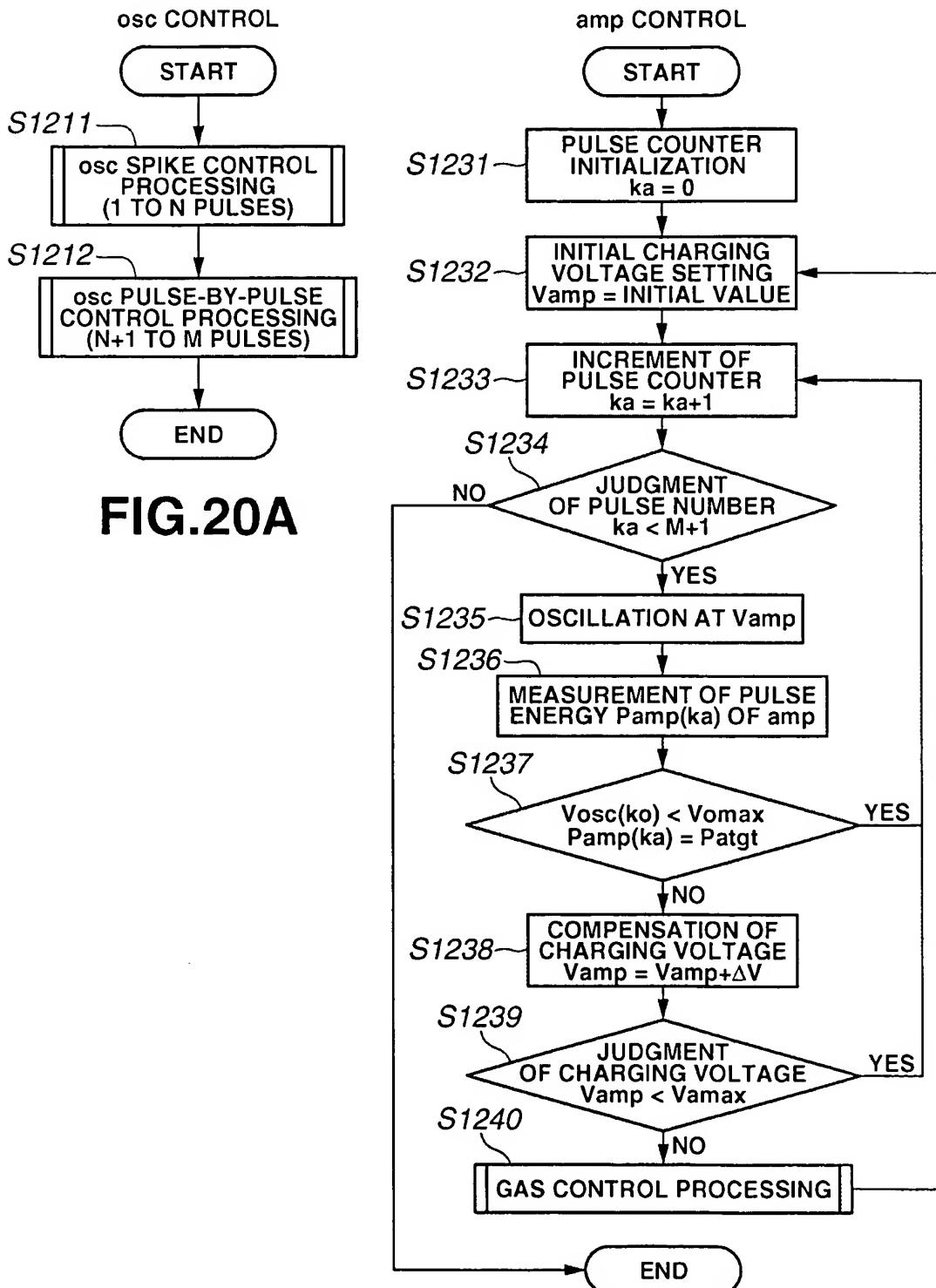


FIG.20B

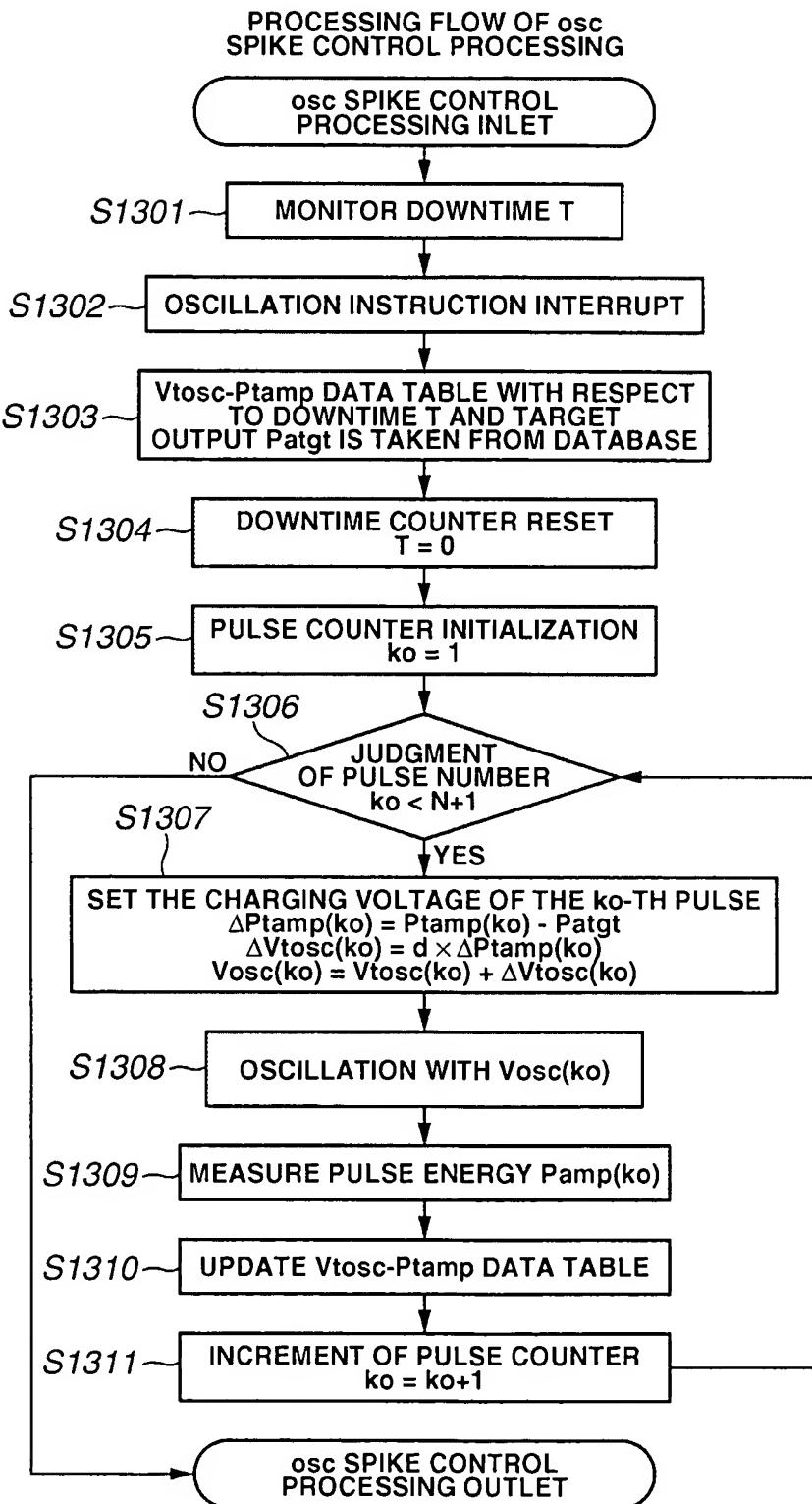


FIG.21

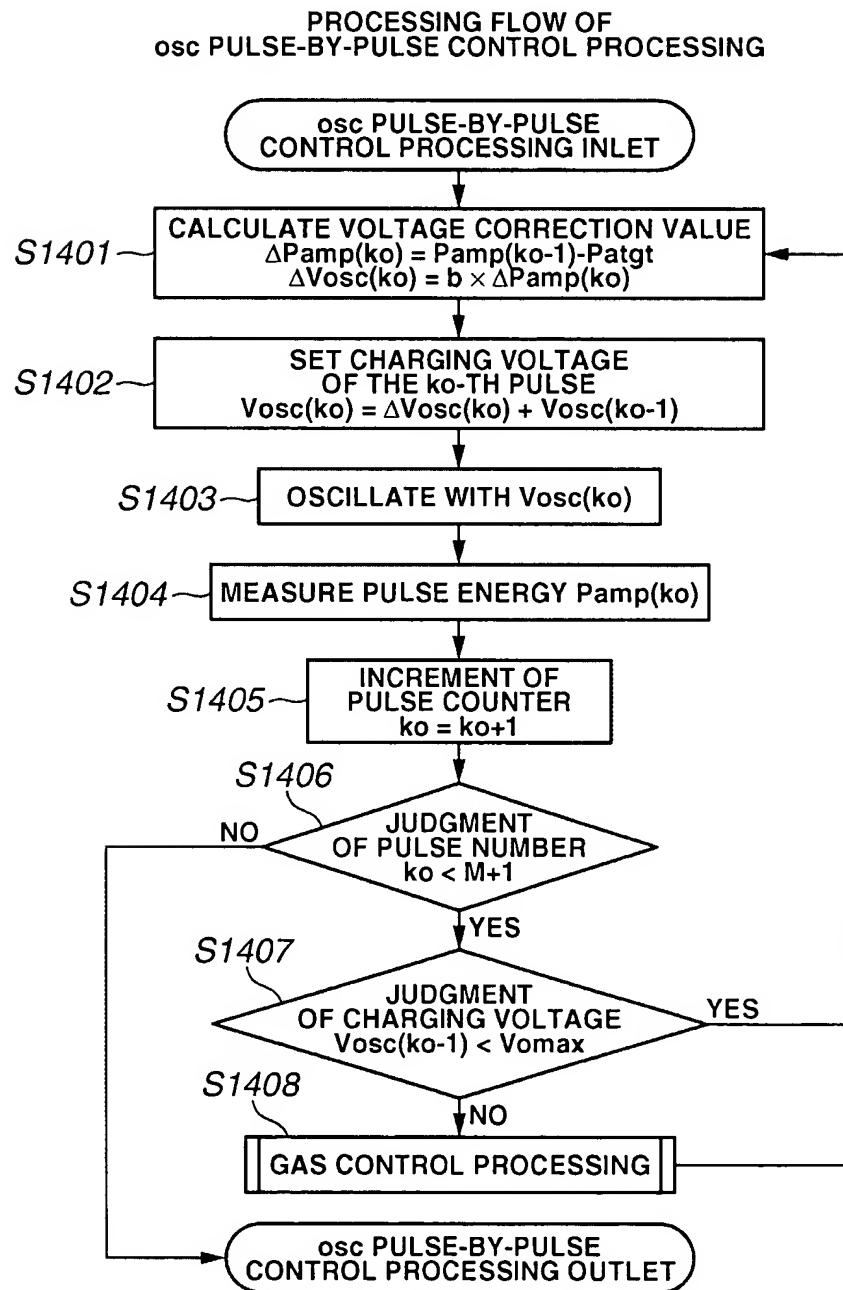


FIG.22

CONTROL FLOWS OF OSCILLATING LASER
AND AMPLIFYING LASER

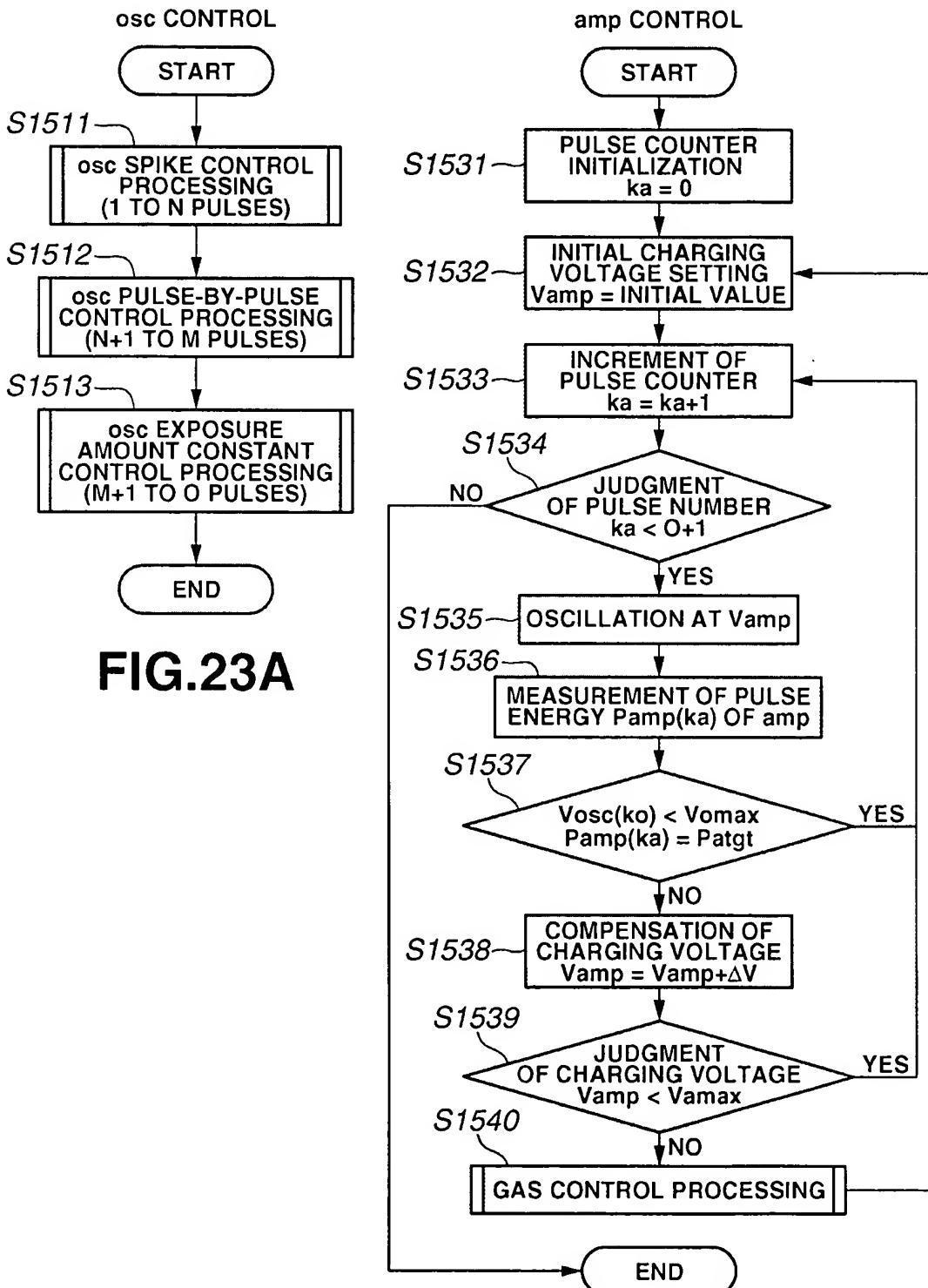


FIG.23B

PROCESSING FLOW OF osc EXPOSURE
 AMOUNT CONSTANT CONTROL PROCESSING

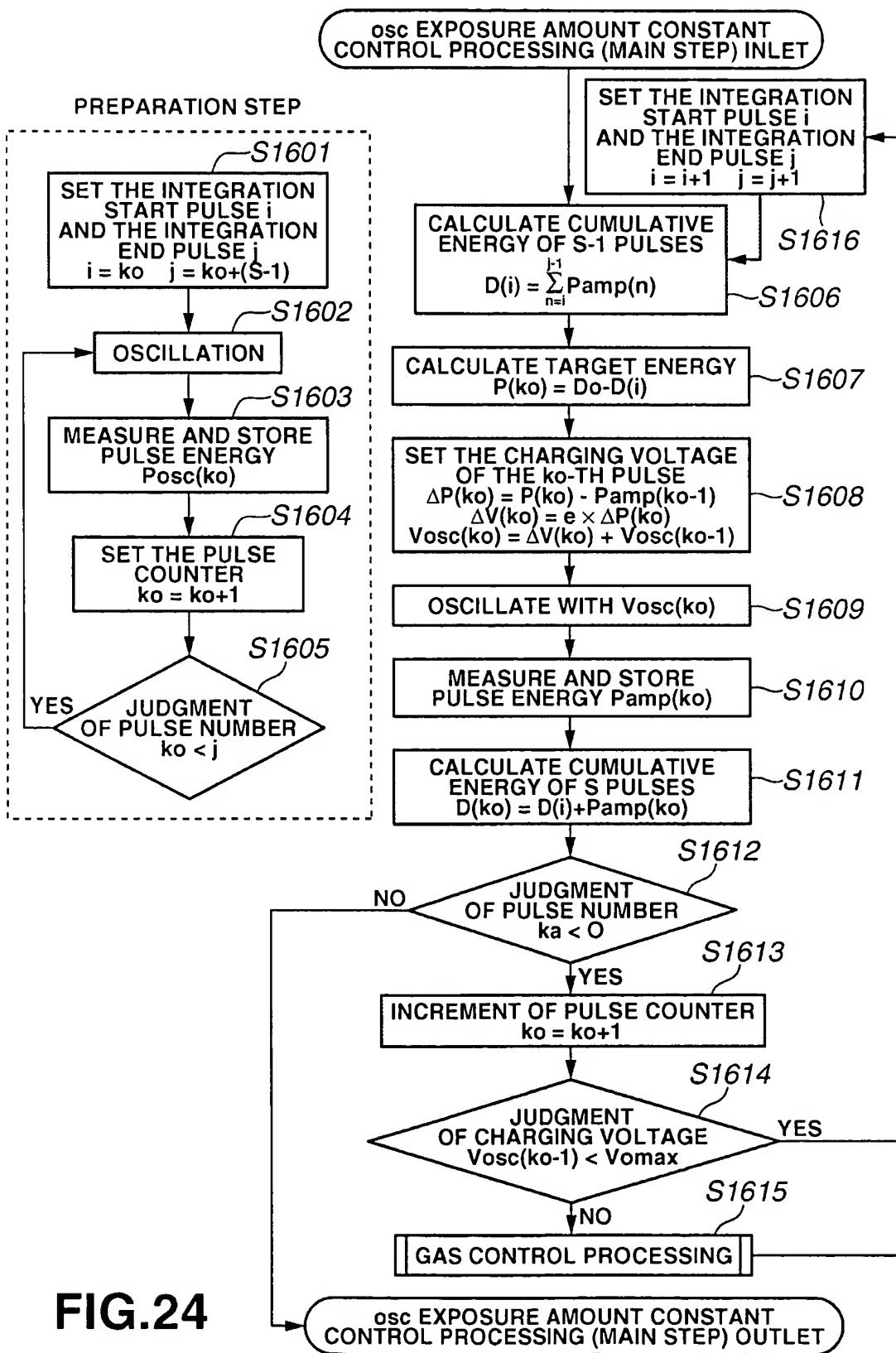
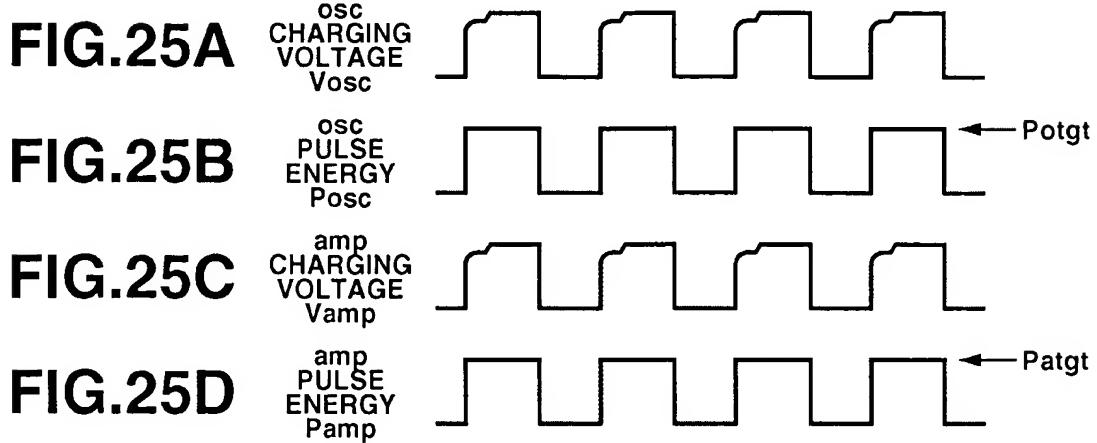


FIG.24

DIAGRAM SHOWING INDIVIDUAL CHARGING VOLTAGES
 AND INDIVIDUAL PULSE ENERGIES IN THIRD CONTROL EXAMPLE



CONTROL FLOWS OF OSCILLATING LASER
 AND AMPLIFYING LASER

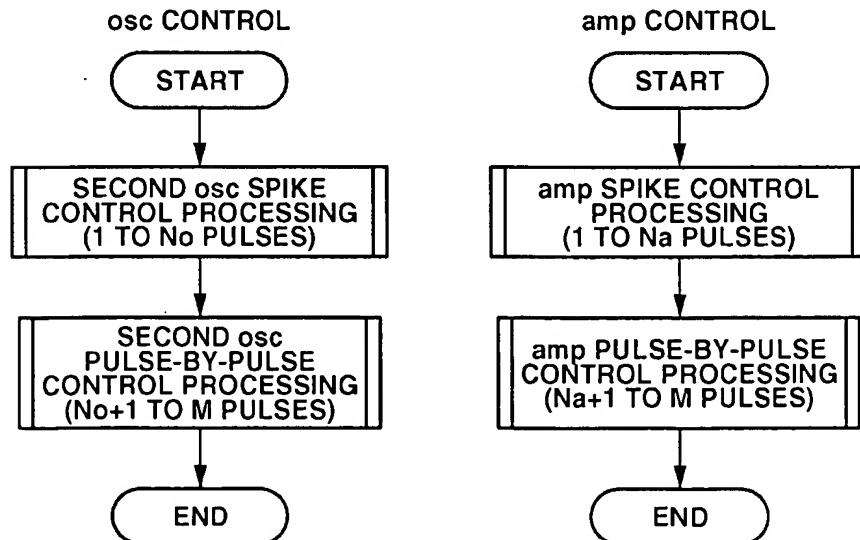


FIG.26A

FIG.26B

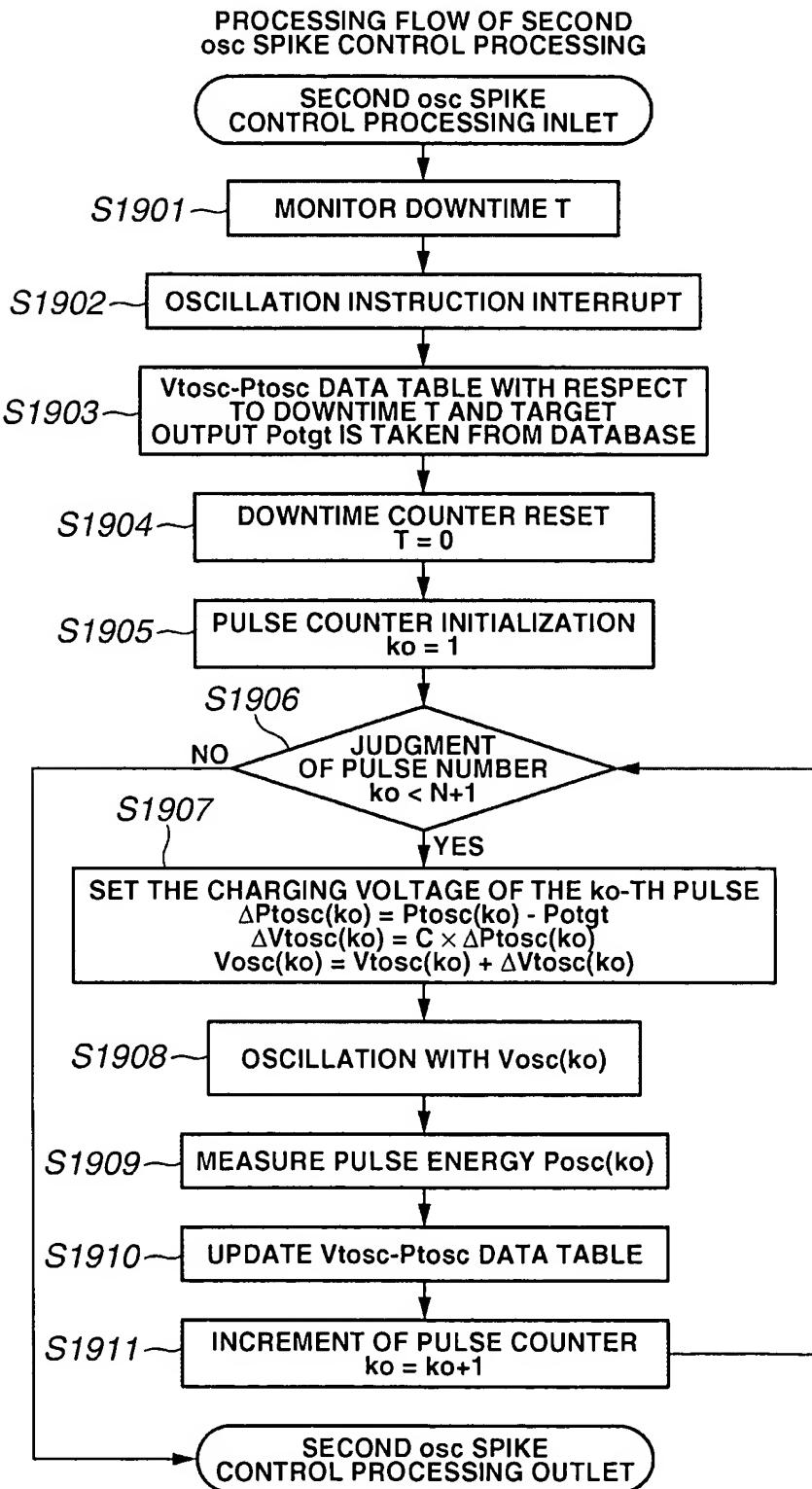


FIG.27

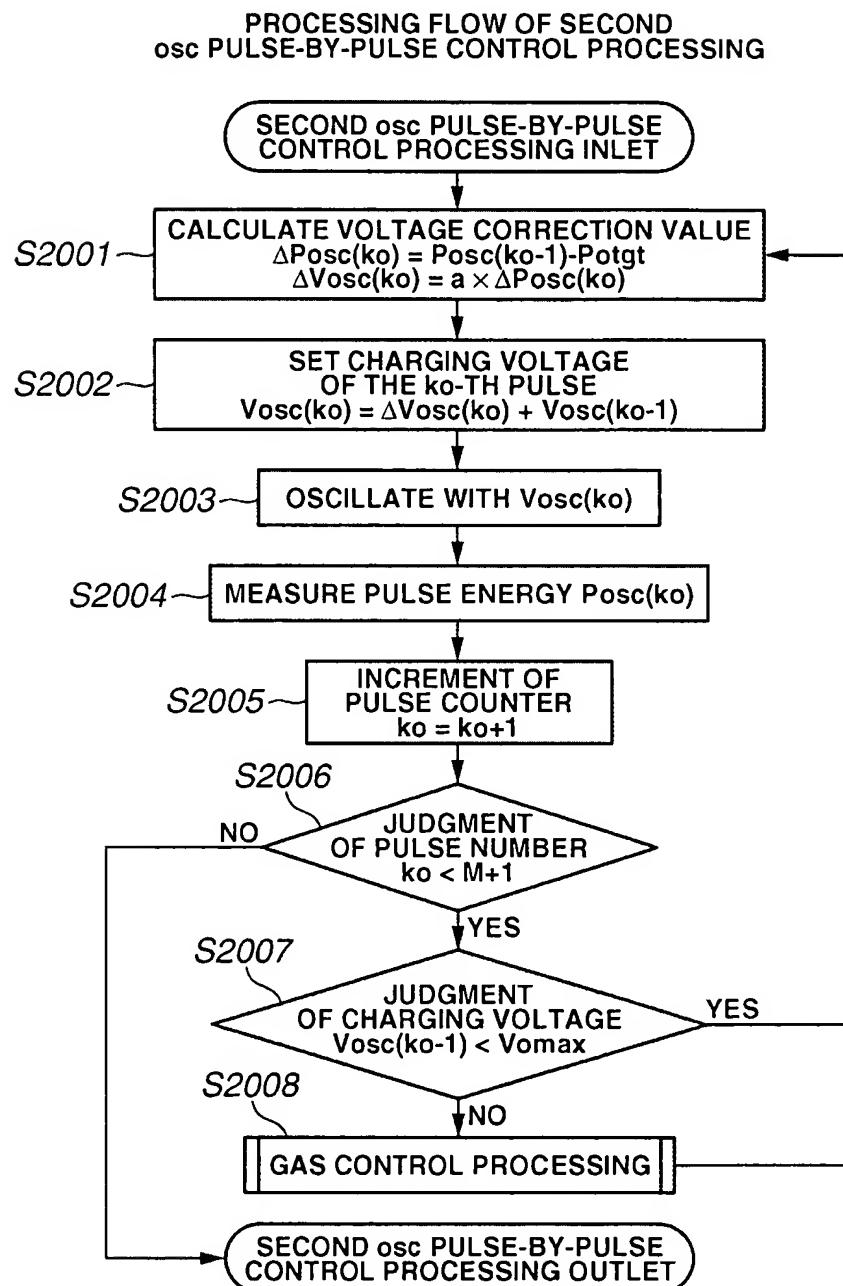


FIG.28

CONTROL FLOWS OF OSCILLATING LASER
AND AMPLIFYING LASER

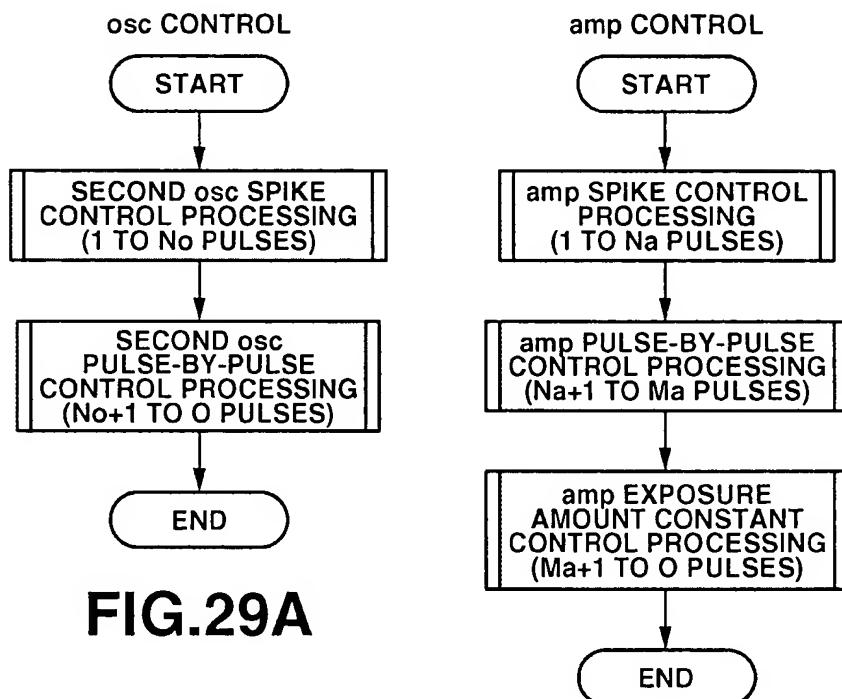


FIG.29B